

Uncertainty Quantification of Properties Models for an MEA System

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CCSI For Accelerating Technology Development











Identify promising concepts Reduce the time for design & troubleshooting

Quantify the technical risk, to enable reaching larger scales, earlier Stabilize the cost during commercial deployment



Presentation Outline

- Research Objectives and Motivation
- Physical Property Model Development
 - Model choice
 - Deterministic modeling
 - Parameter screening
 - Stochastic modeling
- Results
 - Viscosity Model
 - Density Model
 - Surface Tension Model









Research Objectives

- Development of an algorithm for determining physical property models for solvent-based carbon capture with uncertainty quantification (UQ) capability
 - Consider monoethanolamine (MEA) as baseline solvent
 - Use Phoenix Model (University of Texas-Austin) as a starting point
- Validation of models with plant scale data











Model Development Overview

- Identify models that give physical properties as functions of solution conditions (e.g. temperature and composition)
- Deterministic modeling: Calibrate model parameters to fit available experimental data (best fit optimization)
- Parameter screening: Surface response analysis and sensitivity analysis
- Stochastic modeling: Use Bayesian inference to represent model parameters as probability distribution functions











Model Identification

- Use Phoenix model developed by Dr. Rochelle's group at UT Austin as starting point for model choice
- Started with simple/independent properties (viscosity, density, surface tension)
 - Necessary for design and evaluation of separation equipment (e.g. flooding and mass transfer correlations)
- Solution physical properties given as functions of temperature and composition only
 - Composition represented by two independent variables (generally CO₂ loading and MEA weight fraction/percent)



Solution Chemistry

- Represented as ternary MEA-H₂O-CO₂ system in available models and process data
- Simplified electrolytic speciation:

 $2MEA + CO_2 \leftrightarrow MEA^+ + MEACOO^-$

 $MEA + CO_2 + H_2O \leftrightarrow MEA^+ + HCO_3^-$

- Does not consider presence of other ions (H⁺,OH⁻,CO₃²⁻) found to be in negligible concentration
- Electrolyte presence generates complexity in properties modeling (highly non-ideal solution)







Deterministic Modeling

- Function inputs (variables/parameters) and outputs are represented as single values
- General procedure
 - Gather as much relevant data as possible
 - Optimize model parameters to minimize sum of square error (SSE) between data values and model predictions



Parameter Screening

- Determine parameters to which the model is most sensitive
 - UQ necessary for parameters of high sensitivity
 - Parameters of low sensitivity may be eliminated from UQ analysis not only to avoid unnecessary computation, but also for computational tractability
- Response surface method: qualitative parameter screening
- Sensitivity calculation method: quantitative parameter screening









Response Surfaces

- Multivariate Adaptive Regression Splines (MARS) regression technique
 - Reduces mathematical model into non-parametric form that maintains capability of describing relationships between input and output variables
- Computationally inexpensive
- Generated using PSUADE software developed by LLNL
 - Input: Uniform distribution of model variables and parameter and associated output
 - Output: Response surface
- Parameter sensitivity determined by response surface shape







Sensitivity matrix calculation

• For generic physical property:

$$S_{ij} = max \left| \frac{\partial}{\partial \hat{y}_i} \left(\frac{\partial \varphi}{\partial x_j} \right) \right|$$
$$y_i = \overline{y}_i \hat{y}_i$$

- φ : physical property of interest
- x_j : variable
- y_i: actual parameter
- $\overline{y_i}$: baseline parameter value
- \hat{y}_i : parameter deviation term

• Subject to

$$\hat{y}_i^L \le \hat{y}_i \le \hat{y}_i^U \qquad T^L \le T \le T^U \quad \alpha^L \le \alpha \le \alpha^U \qquad X_{MEA}^L \le X_{MEA} \le X_{MEA}^U$$

Normalized version

$$N_{ij} = \frac{S_{ij}}{\max_{i \in [1,n], j \in [1,m]} S_{ij}}$$

- Parameter sensitivity determined by value of N_{ii}
- Method may be more convenient than visualizing surface responses



Stochastic Modeling

- Function inputs and outputs are represented as PDFs
- Sources of uncertainty
 - Process variable measurements (input uncertainty)
 - Physical property measurements (output uncertainty)
 - Functional form of physical property models (model uncertainty)
- Bayesian inference may be used to quantify parametric uncertainty
 - Prior distributions of parameters are updated as additional information is acquired (sampling of experimental data)
 - Markov Chain Monte Carlo (MCMC) method using Gibbs sampling



Bayesian Inference



Viscosity Model

• $\mu_{sln} = \mu_{H_20}(T) \exp\left(\frac{((aX_{MEA}+b)T+cX_{MEA}+d)(\alpha(eX_{MEA}+fT+g)+1)X_{MEA}}{T^2}\right)$

Parameter	Given Value	Calibrated Value	
a	0	-0.0838	
b	0	2.8817	
с	21.186	33.651	
d	2373	1817	
e	0.01015	0.00847	
f	0.0093	0.0103	
g	-2.2589	-2.3890	



Viscosity Model/Data Comparison



Viscosity Model-Sensitivity Analysis

$$N = max \begin{bmatrix} \left| \frac{\partial}{\partial \hat{a}} \left(\frac{\partial \mu}{\partial T} \right) \right| & \left| \frac{\partial}{\partial \hat{a}} \left(\frac{\partial \mu}{\partial X_{MEA}} \right) \right| & \left| \frac{\partial}{\partial \hat{a}} \left(\frac{\partial \mu}{\partial \alpha} \right) \right| \\ \left| \frac{\partial}{\partial \hat{b}} \left(\frac{\partial \mu}{\partial T} \right) \right| & \left| \frac{\partial}{\partial \hat{b}} \left(\frac{\partial \mu}{\partial X_{MEA}} \right) \right| & \left| \frac{\partial}{\partial \hat{b}} \left(\frac{\partial \mu}{\partial \alpha} \right) \right| \\ \left| \frac{\partial}{\partial \hat{c}} \left(\frac{\partial \mu}{\partial T} \right) \right| & \left| \frac{\partial}{\partial \hat{c}} \left(\frac{\partial \mu}{\partial X_{MEA}} \right) \right| & \left| \frac{\partial}{\partial \hat{d}} \left(\frac{\partial \mu}{\partial \alpha} \right) \right| \\ \left| \frac{\partial}{\partial \hat{d}} \left(\frac{\partial 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Viscosity Model-Surface Response Analysis







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Viscosity Model-Posterior Distributions from Bayesian Inference





-2.6

-2.5

-2.4

g

-2.3

-2.2







Density Model

• Three sources of data available for parameter calibration MW_{sln}

 $\rho_{sln} = \frac{1}{X_{MEA}V_{MEA} + X_{H_2O}V_{H_2O} + X_{CO_2}V_{CO_2} + X_{MEA}X_{H_2O}V^* + X_{MEA}X_{H_2O}V^{**}}$

- Solution molecular weight calculation takes electrolyte speciation into account in new model
- Five uncertain parameters

$$- V_{CO_2} = a$$
$$- V^* = b + cX_{MEA}$$

$$-V^{**} = d + eX_{MEA}$$

Baseline Parameter Values		
a	10.2074	
b	-2.2642	
с	3.0059	
d	207	
e	-563.3701	









Density Model/Data Comparison

Results shown for one data source only



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Density Model-Sensitivity Analysis













Density Model-Posterior Distributions from Bayesian Inference



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Surface Tension Model-Original Form

•
$$\sigma_{mix} = \sigma_{H_20} + \sum_{i=CO_2,MEA} \left(1 + \frac{b_i x_i}{(1-a_i)(1+\sum_{j=CO_2,MEA} \frac{a_j}{(1-a_j)} x_j)} \right) (x_i (\sigma_i - \sigma_{H_20}))$$

- Parameters a_i and b_i regressed individually for data sets with given value of MEA weight fraction
- Cannot be used to represent solvents over a range of temperature and composition









New Surface Tension Model

 Continuous function of temperature, CO₂ loading(α), and MEA weight fraction (r) on CO₂-free basis

$$\sigma_{mix} = \sigma_{H_20} + (\sigma_{CO_2} - \sigma_{H_20})f(r,\alpha)x_{CO_2} + (\sigma_{MEA} - \sigma_{H_20})g(r,\alpha)x_{MEA}$$
$$f(r,\alpha) = a + b\alpha + c\alpha^2 + dr + er^2$$
$$g(r,\alpha) = f + g\alpha + h\alpha^2 + ir + jr^2$$

- Functionally similar to original model
- Preserves quality of fit between model and experimental data





Surface Tension Model-Calibrated Parameter Values

Parameter	Value	Parameter	Value
a	2.4558	f	2.3122
b	-1.5311	g	4.5608
С	3.4994	h	-2.3924
d	-5.6398	i	5.3324
е	10.2109	j	-12.0494











Surface Tension Model/Data Comparison



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Surface Tension Model-Sensitivity Analysis

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Surface Tension Model-Posterior Distributions from Bayesian Inference







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Future Work

- Complete physical properties models/UQ for MEA
 - Vapor-liquid equilibrium
 - Heat capacity
 - Thermal conductivity
 - Diffusion coefficient
- Implement models in Aspen Plus® to allow for quantification of uncertainty in process variables (e.g. capture efficiency)
- Validate models with process data
 - UT-Austin Pilot Plant
 - National Carbon Capture Center (NCCC)
- Shift focus to high viscosity solvents



Thank you!

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